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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :  
TAKAHIRO HORIGUCHI ET AL : EXAMINER: KACKAR, RAM N.  
SERIAL NO: 09/855,493 :  
FILED: MAY 16, 2001 : GROUP ART UNIT: 1763  
FOR: SINGLE-SUBSTRATE-PROCESSING:  
APPARATUS FOR SEMICONDUCTOR

AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

In response to the Official Action dated August 1, 2002, please amend the above-identified patent application as follows:

IN THE SPECIFICATION

**Please amend the specification to read as shown below:<sup>1</sup>**

**Please amend the paragraph on page 10, beginning at line 14, to read as shown below:**

The casing 2a of the process chamber 2 is constituted of upper and lower casing parts,

A'

which are detachably joined at a position close to the middle in the vertical direction. The upper casing part, in which the worktable 3 is disposed, has a diameter larger than that of the

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<sup>1</sup>The changes to the claims are shown using underscoring and bracketing in the marked-up copy attached herewith.